



Micro Device and Microfluidic Fabrication with Synchrotron Lithography

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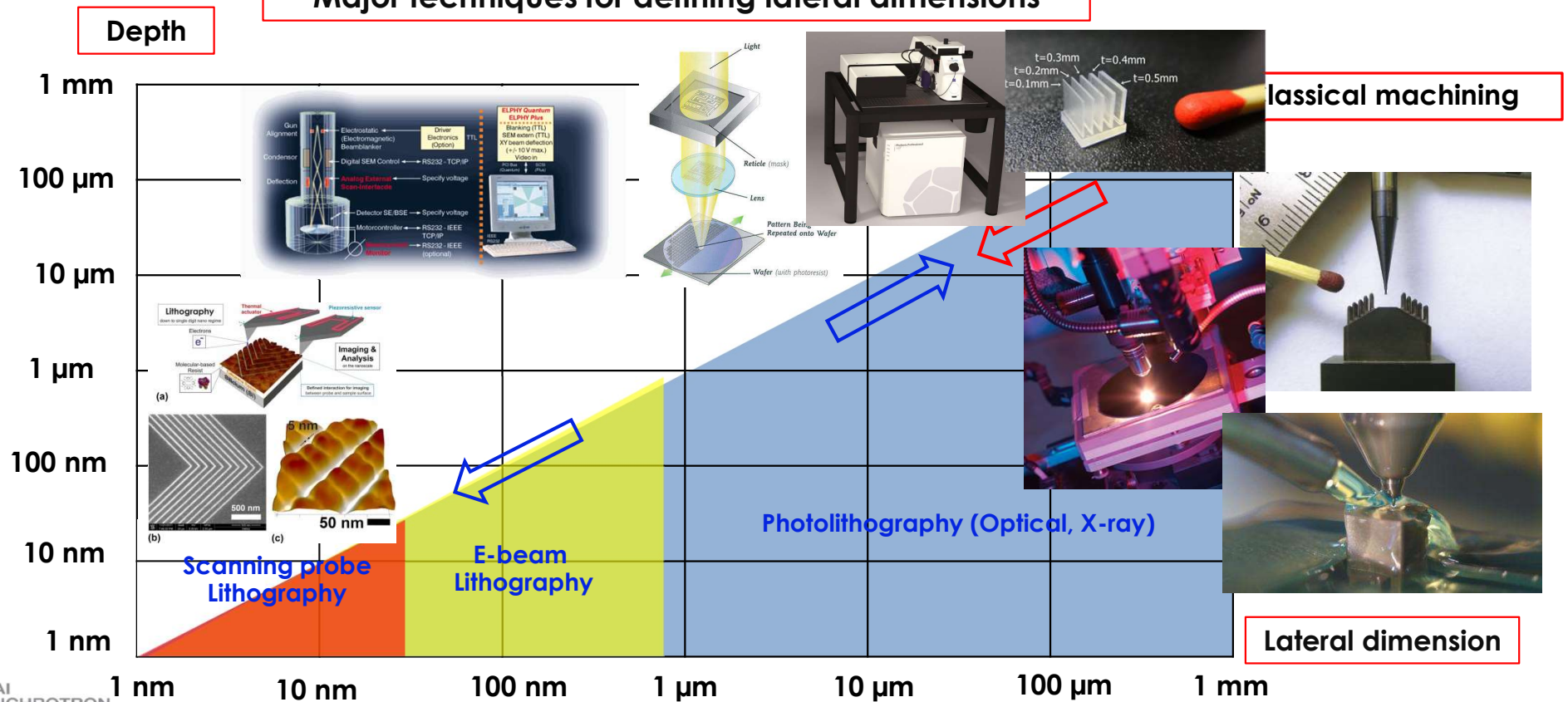
Microfabrication (machining)

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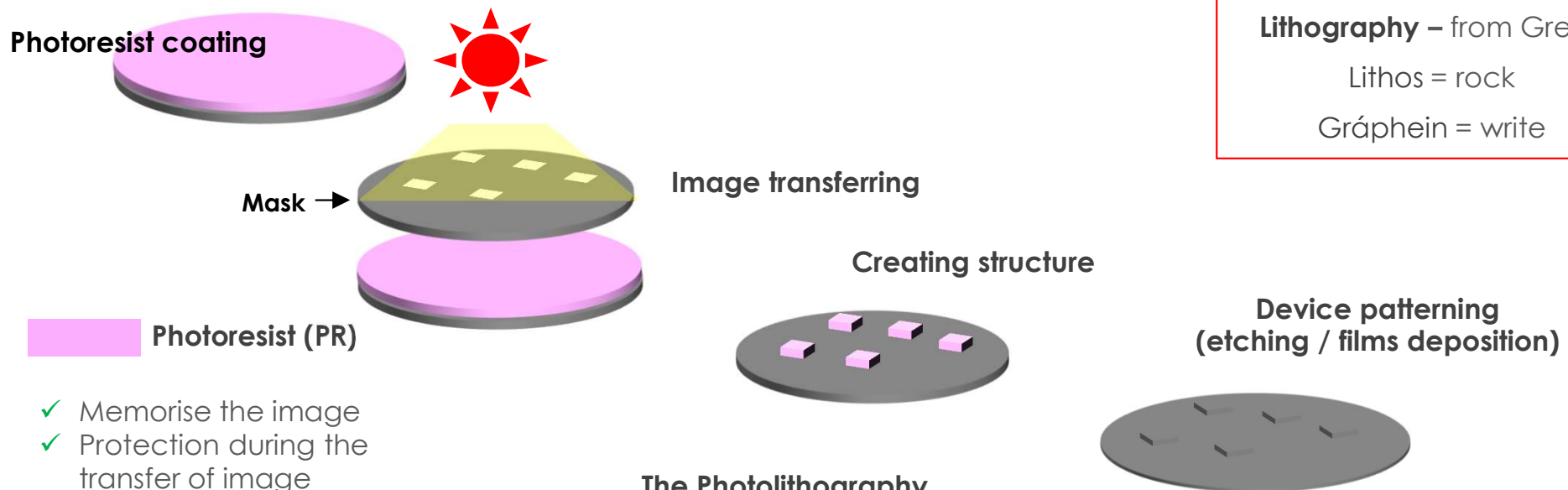
Microfabrication – a process of fabricating mechanical components and benefits of the properties linked to small dimensions (in the **micron** to **millimeter** size range)

Major techniques for defining lateral dimensions



Concept of micropatterning

Photolithography: image transfer process of the device geometry (microstructure or MEMS devices) onto wafer / thin film using light



Lithography – from Greek

Lithos = rock

Gráphein = write

- ✓ Memorise the image
- ✓ Protection during the transfer of image
- ✓ Temporary layer (can be removed)

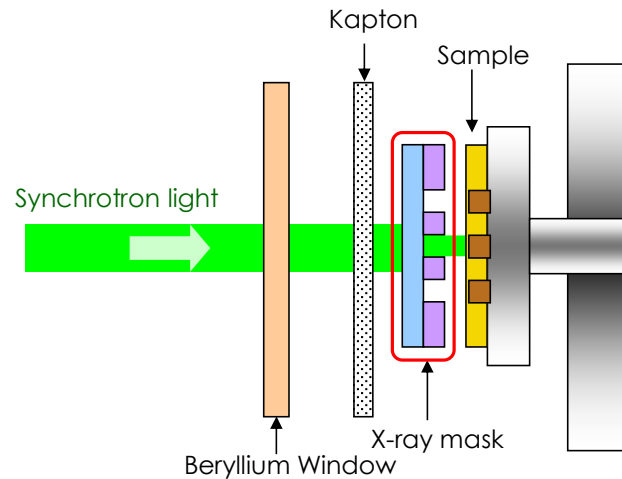
The Photolithography

- ❑ Yields all the dimensions of the device / chip
- ❑ **35% of chip (IC's) or device cost !!!**

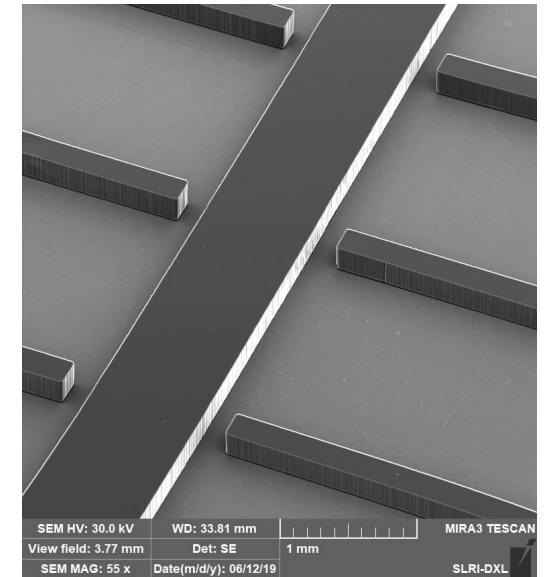
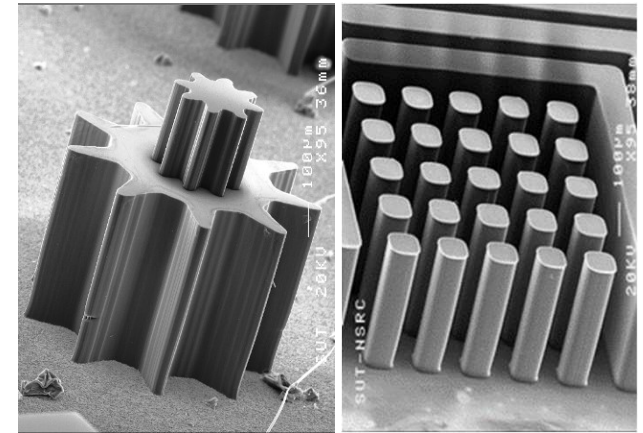
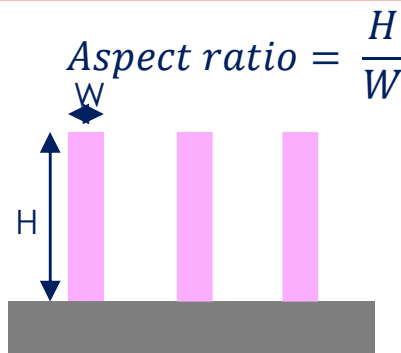
(Currently, at high resolution going up to 70%)

Deep X-ray lithography

□ X-ray from Synchrotron

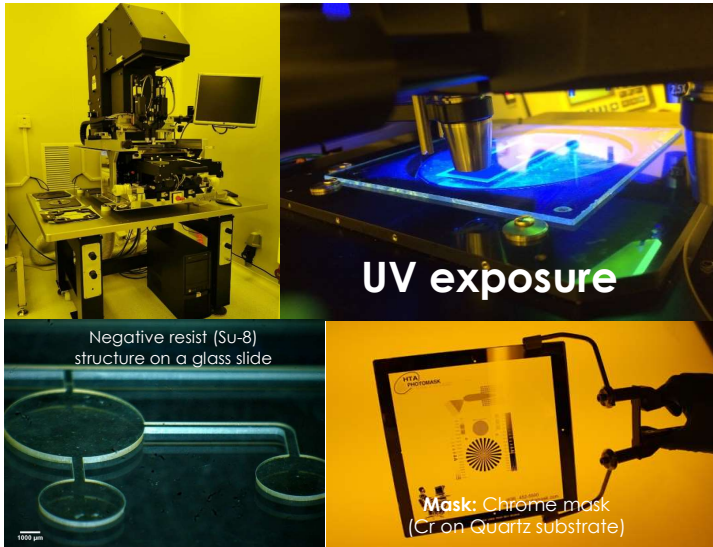


Schematic diagram of X-ray exposure process

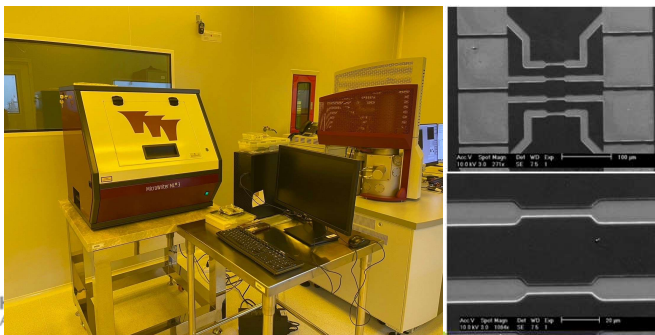


Other lithography

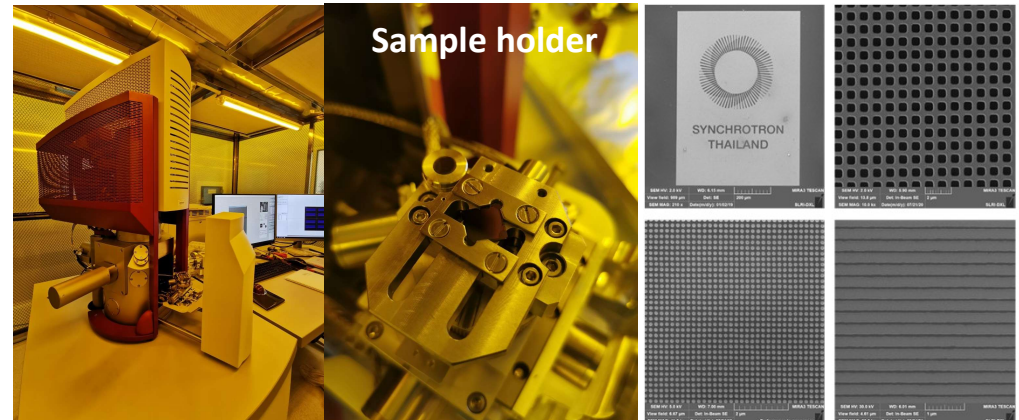
□ UV lithography



□ Direct-write optical lithography



□ Electron beam lithography



Specification for EBL

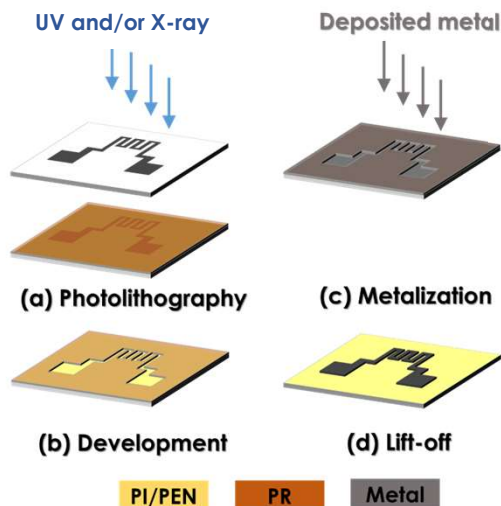
- Electron beam energy: 200eV – 30keV
- Maximum sample size: 2.5x2.5 cm
- Maximum write field size: 1 mm
- Error of write field (WF) accuracy: 1% of WF size
- Designing software: DrawBeam and Clewin (.gds, .dxf, .dbp)
- Probe current: 2pA to 200 nA
- Maximum sample size: 2.5x2.5 cm
- The error stage movement: $\pm 2 \mu\text{m}$

Key features

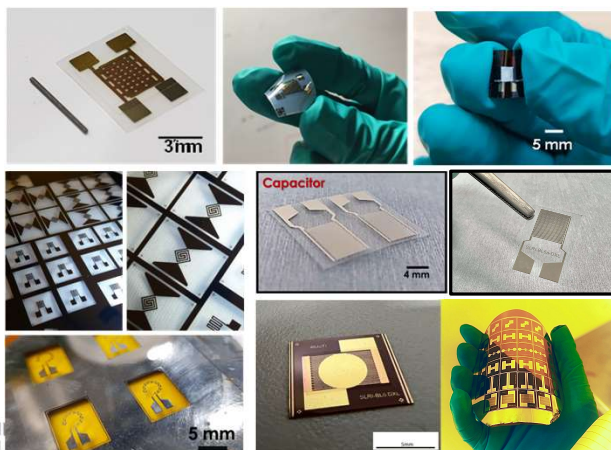
- 195mm x 195mm maximum writing area.
- 230mm x 230mm x 15mm maximum wafer size.
- 0.6 μm , 1 μm , 2 μm and 5 μm minimum feature sizes across the full writing area. 0.4 μm minimum feature size available as an option.

Gas sensing application

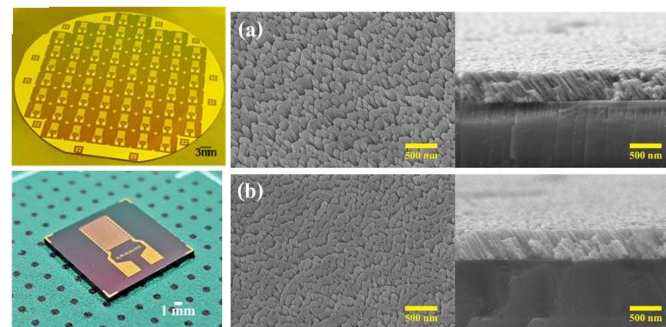
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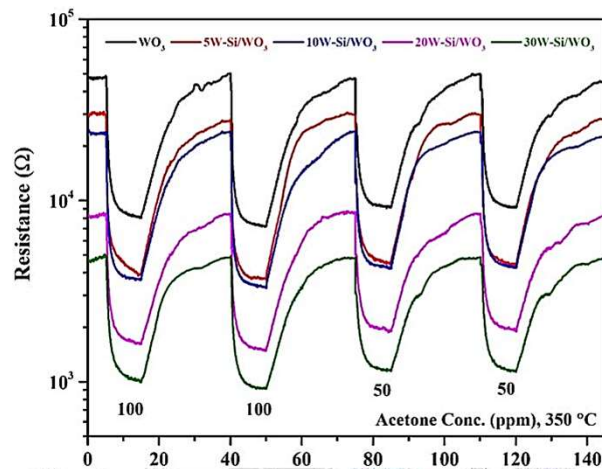
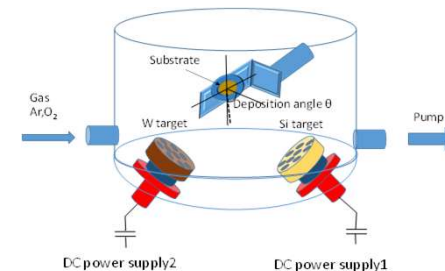
Low-cost fabricated sensors on plastic foil, disposal, reusable, wearable applications !!!



Acetone gas sensor based on Si-doped WO_3 nanorods prepared by magnetron co-sputtering

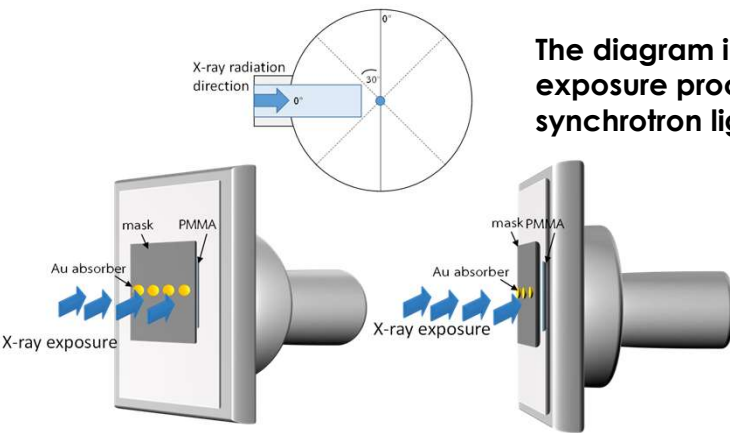


SEM images of (a) pure WO_3 and (b) Si-doped WO_3 nanorods deposited onto the sensor substrate after annealing

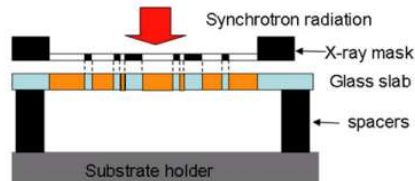
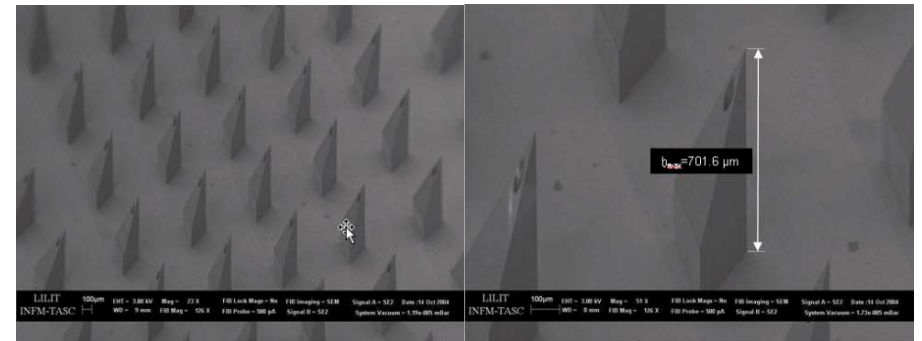


- ⊙ The potential of high-sensitivity acetone gas sensor at low concentration
- ⊙ an effective tool for diabetes non-invasive monitoring

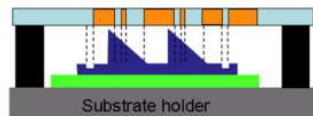
Microneedle arrays fabricated by Deep X-ray lithography



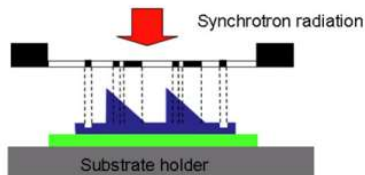
The diagram indicates the X-ray exposure process using synchrotron light



Exposure of glass slab through X-ray mask



Alignment of the sawtooth sample with the exposed glass slab under the microscope



Exposure of aligned sawtooth sample through the X-ray mask

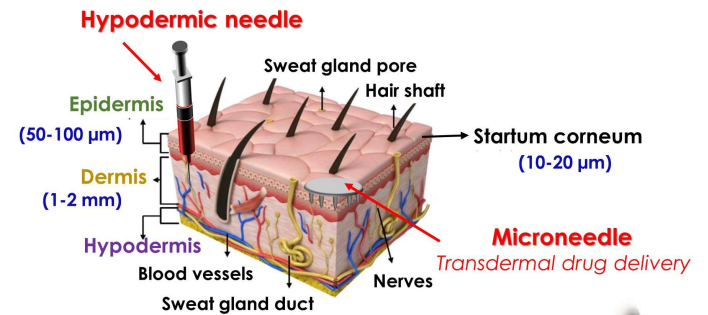
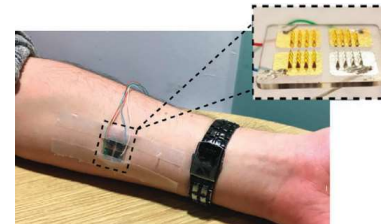


Fig. 1 Illustrated of needle in human skin

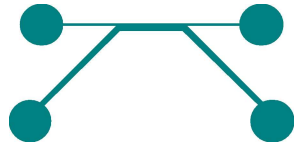


Medical



Aesthetic enhancements

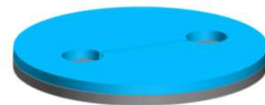
Fabrication of master mould for microfluidics



In collaboration with SUT
 “Sperm sorting
 using microfluidics device”

SUT-SLRI-BL6a:DXL

Image transfer
 (Photolithography)



Ni electrodeposition



PR stripping



Soft-lithography
 (Replicated by elastomer)

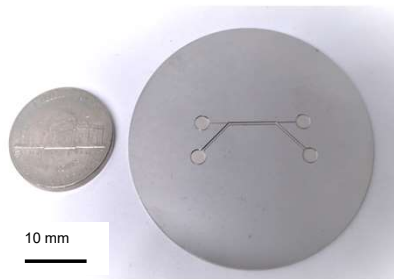
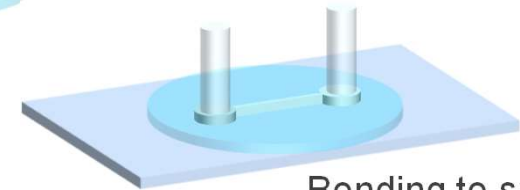
Casting PDMS on the
 master



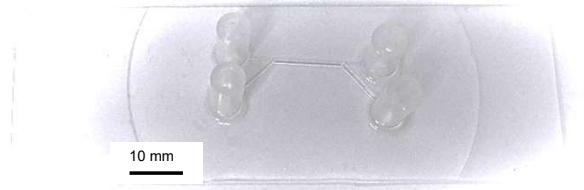
Peel off



Bonding to substrate



PR stripping



SUS

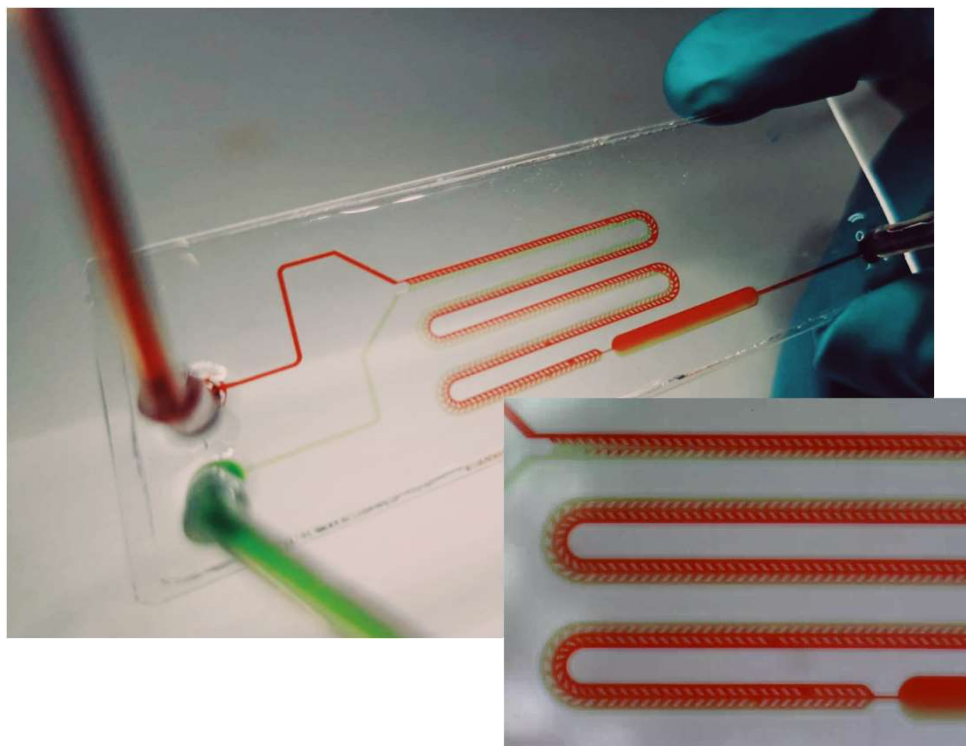
PR

Ni

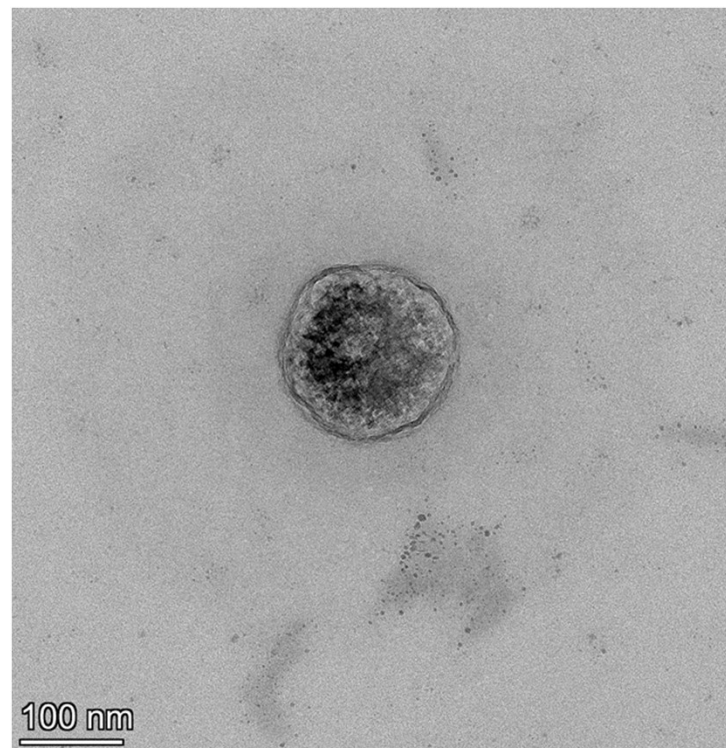
PDMS

SiO₂

Synthesis of lipid nanoparticles by microfluidics

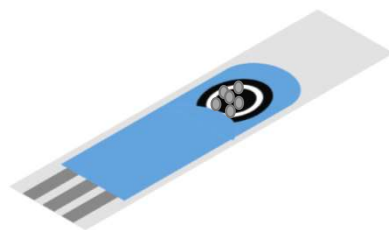
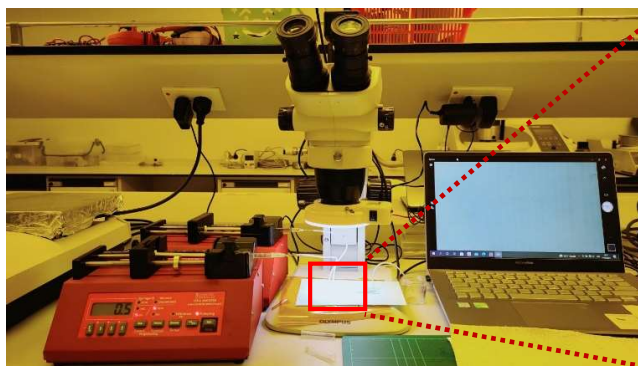
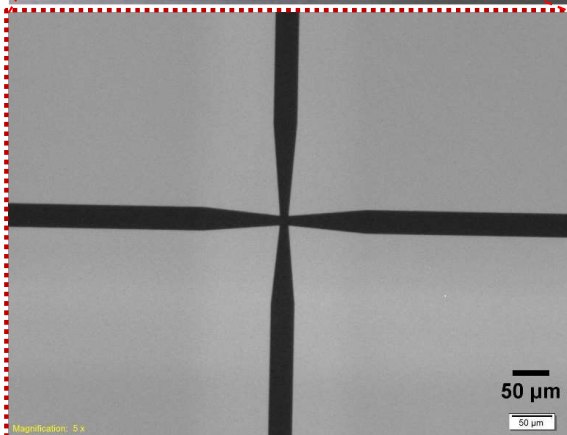
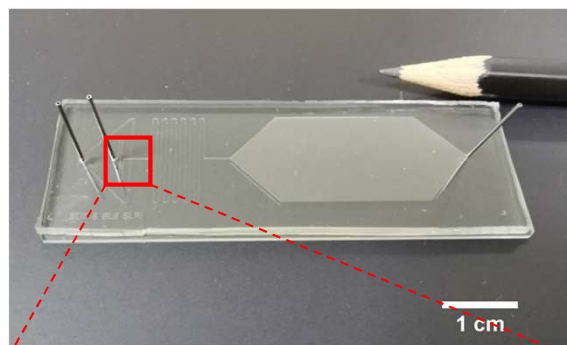


Micromixer fabricated using X-ray lithography & Soft lithography for synthesis of lipidnanoparticles

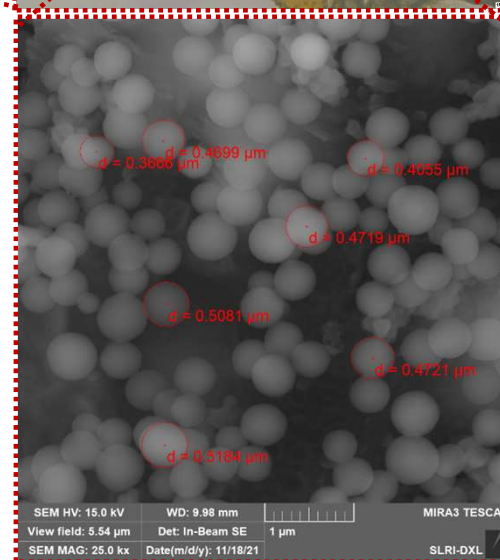
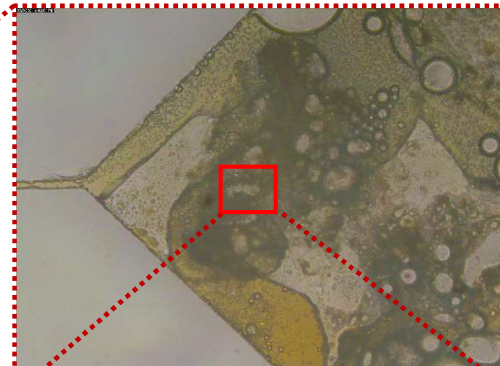


TEM of Lipidnanoparticles synthesized by fabricated micromixer

The polypyrrole chemistry developed with microfluidic encapsulation

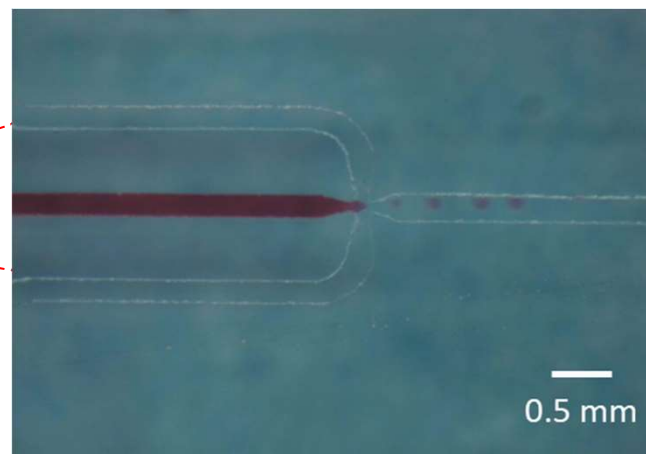
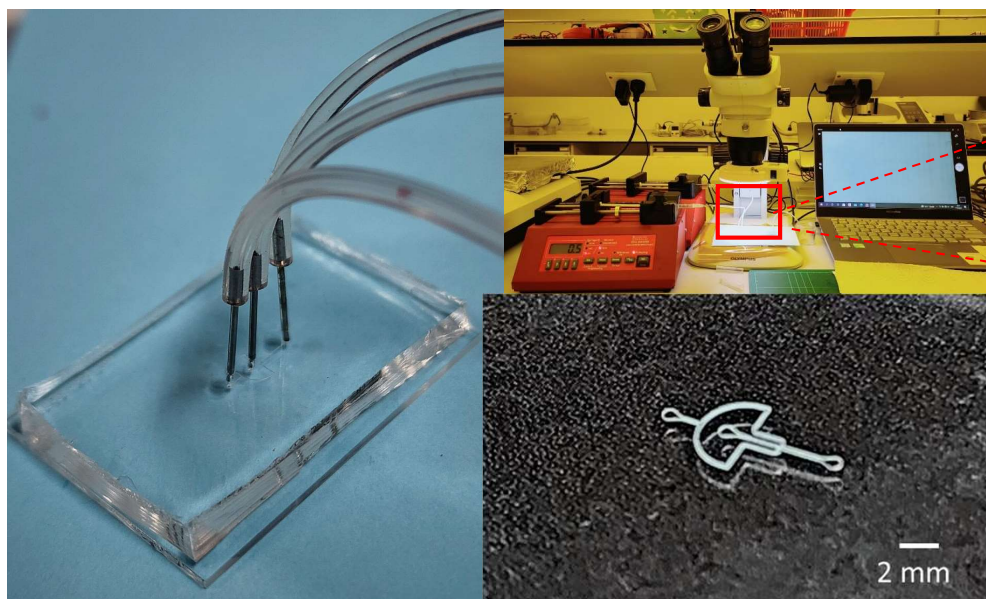


Polypyrrole capsules (10-micron channel)
amount loading 0.2 mg

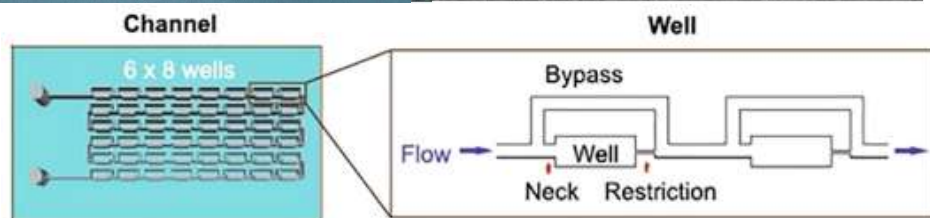


The microchannel widths 10 μm, high 50 μm and using flow rate of Pyrrole 0.4 μL/min : FeCl₃ 0.10 μL/min

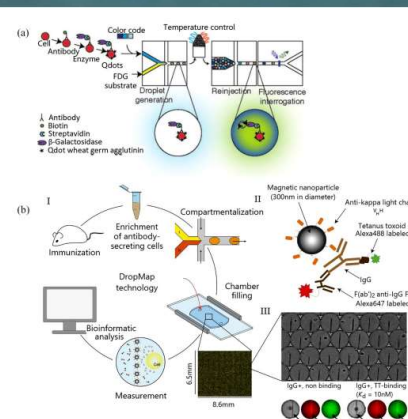
Synthesis of microdroplet



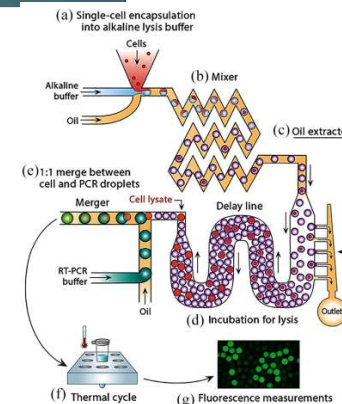
The microchannel widths are 150 μm , high 100 μm and using a flow rate of oil 20 $\mu\text{L}/\text{min}$: red water 2 $\mu\text{L}/\text{min}$



Drug screen of tumor cells

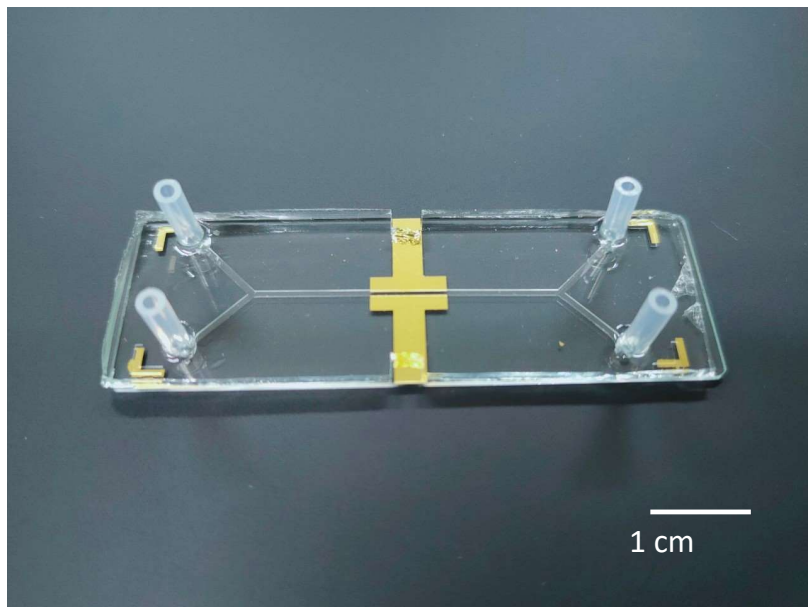


Cell recognition

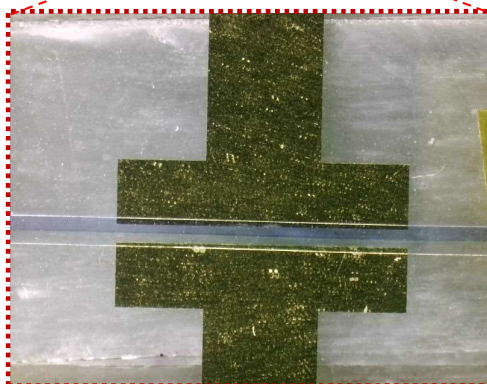


Single-cell RT-PCR

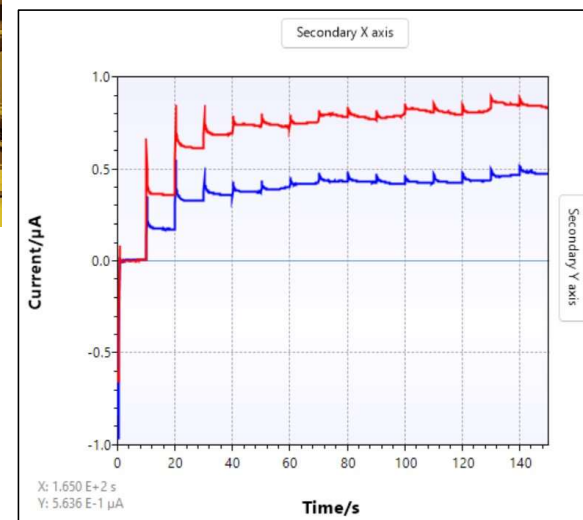
The biofuel cell



The microchannel widths are 1 mm, high 100 μm and using a flow rate of catholyte 200 $\mu\text{L}/\text{min}$ and 500 $\mu\text{L}/\text{min}$: anolyte 200 $\mu\text{L}/\text{min}$ and 500 $\mu\text{L}/\text{min}$

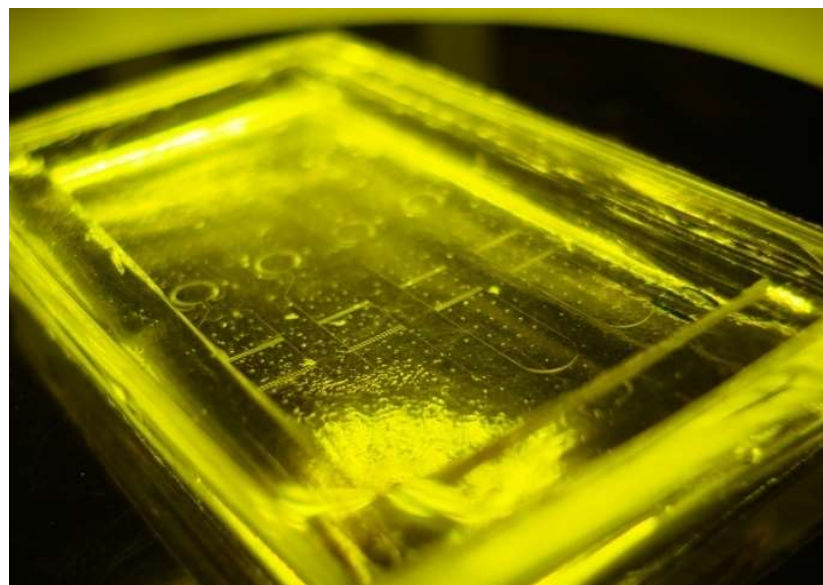


The catholyte and anolyte solution

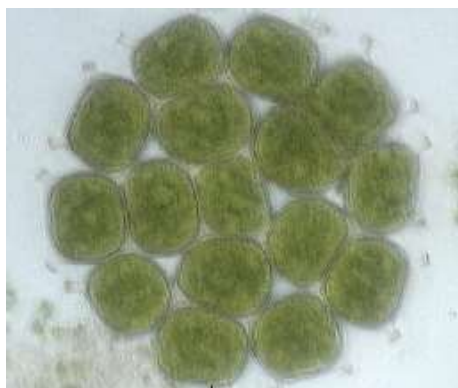
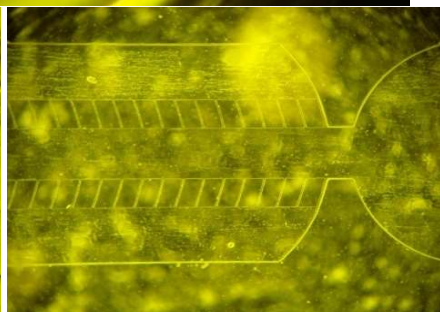


Potential with current curves

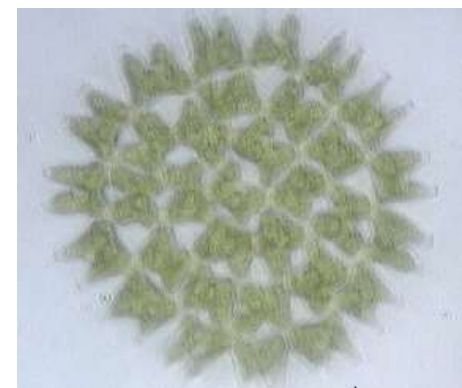
Other microfluidic devices



Ni based μ -fluidic chips
on CaF_2 window



Pediasium duplex
in JM media



Pediasium duplex
in BG11 media

THANK YOU



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CENTRAL LAB

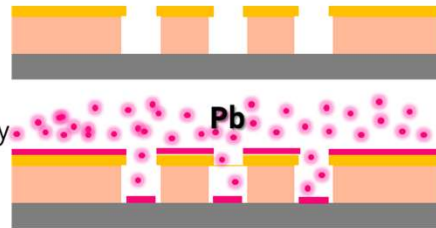


THA
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NATI

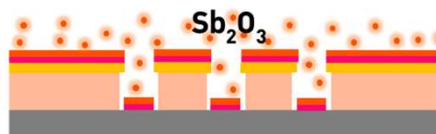
Fabrication of Gunshot Residues (GSR)

The GSR pattern by **EBL**

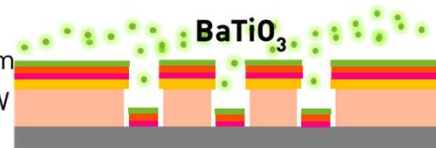
Thin film of **Pb**, thick ~300 nm by
rate 22.16 nm/min with at 75 W



Thin film of **Sb₂O₃**, thick ~300 nm
by rate 9.68 nm/min with at 75 W



Thin film of **BaTiO₃**, thick ~300 nm
by rate 3.79 nm/min with at 100 W



Lift-off to remove resist and
LOR5B using PG remover

